

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Seung-un KIM, et al.

Serial No.

[Division of Serial No. 10/084,198, filed February 28, 2002]

Filed: March 16, 2004

For: APPARATUS AND METHOD FOR SUPPLYING CHEMICALS
IN CHEMICAL MECHANICAL POLISHING SYSTEMS

PRELIMINARY AMENDMENT

Commissioner for Patents
Alexandria, VA 22313-1450

Sir:

INTRODUCTORY COMMENT(S)

A listing of claims begins on page 2 of this paper.

Remarks are on page 4 of this paper.

Prior to calculation of the statutory filing fee, kindly amend the application identified above as follows: